## Chuan Seng Tan

# List of Publications by Year in Descending Order

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The third column is the impact factor (IF) of the journal, and the fourth column is the number of citations of the article.

2,808 26 267 40 h-index g-index citations papers 3,526 2.9 339 5.33 avg, IF L-index ext. citations ext. papers

#	Paper	IF	Citations
267	Grating and hole-array enhanced germanium lateral p-i-n photodetectors on an insulator platform <i>Optics Express</i> , <b>2022</b> , 30, 4706-4717	3.3	O
266	High-Performance Back-Illuminated Ge0.92Sn0.08/Ge Multiple-Quantum-Well Photodetector on Si Platform For SWIR Detection. <i>IEEE Journal of Selected Topics in Quantum Electronics</i> , <b>2022</b> , 28, 1-9	3.8	6
265	Metal-semiconductor-metal Photodetectors on a GeSn-on-insulator Platform for 2 m Applications. <i>IEEE Photonics Journal</i> , <b>2022</b> , 1-1	1.8	2
264	In 0.3 Ga 0.7 As heterojunction bipolar transistor grown on GeSi substrate for high-frequency application. <i>Materials Science in Semiconductor Processing</i> , <b>2022</b> , 146, 106663	4.3	
263	Transferable single-layer GeSn nanomembrane resonant-cavity-enhanced photodetectors for 2 h band optical communication and multi-spectral short-wave infrared sensing <i>Nanoscale</i> , <b>2022</b> , 14, 7341	-7 <i>3</i> 749	2
262	Direct bandgap GeSn nanowires enabled with ultrahigh tension from harnessing intrinsic compressive strain. <i>Applied Physics Letters</i> , <b>2022</b> , 120, 202103	3.4	
261	Advanced 3D Integration Technologies in Various Quantum Computing Devices. <i>IEEE Open Journal of Nanotechnology</i> , <b>2021</b> , 1-1	2.1	O
260	Suspended germanium membranes photodetector with tunable biaxial tensile strain and location-determined wavelength-selective photoresponsivity. <i>Applied Physics Letters</i> , <b>2021</b> , 119, 19110	6 <sup>3.4</sup>	1
259	1D photonic crystal direct bandgap GeSn-on-insulator laser. <i>Applied Physics Letters</i> , <b>2021</b> , 119, 201101	3.4	7
258	Surface plasmon enhanced GeSn photodetectors operating at 2 Jim. <i>Optics Express</i> , <b>2021</b> , 29, 8498-8509	93.3	7
257	TSV-integrated surface electrode ion trap for scalable quantum information processing. <i>Applied Physics Letters</i> , <b>2021</b> , 118, 124003	3.4	4
256	High Performance Flexible Visible-Blind Ultraviolet Photodetectors with Two-Dimensional Electron Gas Based on Unconventional Release Strategy. <i>ACS Nano</i> , <b>2021</b> , 15, 8386-8396	16.7	13
255	Corner-Promoted Focus Enhancement of Light in Conical Holes for Extraordinary Optical Transmission. <i>IEEE Sensors Journal</i> , <b>2021</b> , 21, 9081-9089	4	O
254	Sub-mA/cm2 Dark Current Density, Buffer-Less Germanium (Ge) Photodiodes on a 200-mm Ge-on-Insulator Substrate. <i>IEEE Transactions on Electron Devices</i> , <b>2021</b> , 68, 1730-1737	2.9	4
253	Biaxially strained germanium crossbeam with a high-quality optical cavity for on-chip laser applications. <i>Optics Express</i> , <b>2021</b> , 29, 14174-14181	3.3	2
252	Monolithic Germanium-Tin Pedestal Waveguide for Mid-Infrared Applications. <i>IEEE Photonics Journal</i> , <b>2021</b> , 13, 1-11	1.8	
251	High-Sensitivity and Mechanically Compliant Flexible Ge Photodetectors with a Vertical pill Configuration. <i>ACS Applied Electronic Materials</i> , <b>2021</b> , 3, 1780-1786	4	1

### (2020-2021)

250	Gourd-shaped hole array germanium (Ge)-on-insulator photodiodes with improved responsivity and specific detectivity at 1,550 nm. <i>Optics Express</i> , <b>2021</b> , 29, 16520-16533	3.3	3
249	Large-Scale Fabrication of Surface Ion Traps on a 300 mm Glass Wafer. <i>Physica Status Solidi (B):</i> Basic Research, <b>2021</b> , 258, 2000589	1.3	2
248	Structural Integrity of 3-D Metal <b>I</b> hsulator <b>M</b> etal Capacitor Embedded in Fully Filled Cu Through-Silicon via. <i>IEEE Transactions on Components, Packaging and Manufacturing Technology</i> , <b>2021</b> , 11, 918-921	1.7	2
247	Corrections to Btructural Integrity of 3-D Metal <b>I</b> hsulatorMetal Capacitor Embedded in Fully Filled Cu Through-Silicon ViaII <i>IEEE Transactions on Components, Packaging and Manufacturing Technology, <b>2021</b>, 11, 1148-1148</i>	1.7	
246	. IEEE Sensors Journal, <b>2021</b> , 1-1	4	3
245	A highly ordered and damage-free Ge inverted pyramid array structure for broadband antireflection in the mid-infrared. <i>Journal of Materials Chemistry C</i> , <b>2021</b> , 9, 9884-9891	7.1	4
244	RF Performance Benchmarking of TSV Integrated Surface Electrode Ion Trap for Quantum Computing. <i>IEEE Transactions on Components, Packaging and Manufacturing Technology</i> , <b>2021</b> , 1-1	1.7	O
243	Low-power and high-detectivity Ge photodiodes by in-situ heavy As doping during Ge-on-Si seed layer growth. <i>Optics Express</i> , <b>2021</b> , 29, 2940-2952	3.3	7
242	A review of silicon-based wafer bonding processes, an approach to realize the monolithic integration of Si-CMOS and IIIIV-on-Si wafers. <i>Journal of Semiconductors</i> , <b>2021</b> , 42, 023106	2.3	9
241	GeSn-on-insulator dual-waveband resonant-cavity-enhanced photodetectors at the 2 $\mu$ m and 1.55 $\mu$ m optical communication bands. <i>Optics Letters</i> , <b>2021</b> , 46, 3809-3812	3	4
240	Design and Fabrication of Grating Couplers for the Optical Addressing of Trapped Ions. <i>IEEE Photonics Journal</i> , <b>2021</b> , 13, 1-6	1.8	Ο
239	Effects of high-temperature thermal annealing on GeSn thin-film material and photodetector operating at 2 Jim. <i>Journal of Alloys and Compounds</i> , <b>2021</b> , 872, 159696	5.7	1
238	Highly Tensile-Strained Self-Assembled Ge Quantum Dots on InP Substrates for Integrated Light Sources. <i>ACS Applied Nano Materials</i> , <b>2021</b> , 4, 897-906	5.6	4
237	Band Structure of Strained $\frac{g}{1-x}\sim \frac{sn}{x}$ Alloy: A Full-Zone 30-Band $\frac{g}{x}$ Model. <i>IEEE Journal of Quantum Electronics</i> , <b>2020</b> , 56, 1-8	2	1
236	Dark current analysis of germanium-on-insulator vertical p-i-n photodetectors with varying threading dislocation density. <i>Journal of Applied Physics</i> , <b>2020</b> , 127, 203105	2.5	20
235	Design and Development of Single-Qubit Ion Trap on Glass and Si Substrates With RF Analysis and Performance Benchmarking. <i>IEEE Transactions on Components, Packaging and Manufacturing Technology</i> , <b>2020</b> , 10, 1221-1231	1.7	3
234	Heat transfer suppression by suspended droplets on microstructured surfaces. <i>Applied Physics Letters</i> , <b>2020</b> , 116, 233703	3.4	8
233	Highly Compact Linear Variable Filter in the Mid Infrared Region for Acetone Level Monitoring. <i>IEEE Sensors Journal</i> , <b>2020</b> , 20, 4171-4178	4	1

232	High-Frequency Characteristics of InGaP/GaAs Double Heterojunction Bipolar Transistor Epitaxially Grown on 200 mm Ge/Si Wafers. <i>IEEE Journal of the Electron Devices Society</i> , <b>2020</b> , 8, 122-125	2.3	O
231	Effects of precursors purity on graphene quality: Synthesis and thermoelectric effect. <i>AIP Advances</i> , <b>2020</b> , 10, 045016	1.5	1
230	Growth and Characterizations of GeSn Films with High Sn Composition by Chemical Vapor Deposition (CVD) Using Ge2H6 and SnCl4 for Mid-IR Applications. <i>ECS Transactions</i> , <b>2020</b> , 98, 91-98	1	5
229	High-efficiency GeSn/Ge multiple-quantum-well photodetectors with photon-trapping microstructures operating at 2 $\bar{\mu}$ m. <i>Optics Express</i> , <b>2020</b> , 28, 10280-10293	3.3	39
228	Resonant-cavity-enhanced responsivity in germanium-on-insulator photodetectors. <i>Optics Express</i> , <b>2020</b> , 28, 23739-23747	3.3	10
227	High speed and ultra-low dark current Ge vertical p-i-n photodetectors on an oxygen-annealed Ge-on-insulator platform with GeO surface passivation. <i>Optics Express</i> , <b>2020</b> , 28, 23978-23990	3.3	13
226	Photo detection and modulation from 1,550 to 2,000 nm realized by a GeSn/Ge multiple-quantum-well photodiode on a 300-mm Si substrate. <i>Optics Express</i> , <b>2020</b> , 28, 34772-34786	3.3	12
225	Ge-on-insulator lateral p-i-n waveguide photodetectors for optical communication. <i>Optics Letters</i> , <b>2020</b> , 45, 6683-6686	3	2
224	Improved thin film quality and photoluminescence of N-doped epitaxial germanium-on-silicon using MOCVD. <i>Optical Materials Express</i> , <b>2020</b> , 10, 1	2.6	1
223	Ar/N2 Plasma Induced Metastable CuxNy for Cu-Cu Direct Bonding. ECS Transactions, 2020, 98, 203-210	1	2
222	Performance Comparison of High Resistivity Silicon, Silicon with Grounding Plane and Glass as Substrate of Ion Trap for Quantum Information Processing <b>2020</b> ,		1
221	Theoretical design of mid-infrared interband cascade lasers in SiGeSn system. <i>New Journal of Physics</i> , <b>2020</b> , 22, 083061	2.9	1
220	Glass Substrate Interposer for TSV-integrated Surface Electrode Ion Trap <b>2020</b> ,		2
219	EO Integration of Planar Ion Trap and Silicon Photonics for Optical Addressing in Quantum Computing <b>2020</b> ,		1
218	. IEEE Transactions on Components, Packaging and Manufacturing Technology, <b>2020</b> , 10, 679-685	1.7	2
217	The effects of strain and composition on the conduction-band offset of direct band gap type-I GeSn/GeSnSi quantum dots for CMOS compatible mid-IR light source. <i>Semiconductor Science and Technology</i> , <b>2020</b> , 35, 025008	1.8	2
216	Condition Monitoring of DC-Link Capacitors Using Goertzel Algorithm for Failure Precursor Parameter and Temperature Estimation. <i>IEEE Transactions on Power Electronics</i> , <b>2020</b> , 35, 6386-6396	7.2	26
215	Modulation of light absorption in flexible GeSn metallemiconductorfhetal photodetectors by mechanical bending. <i>Journal of Materials Chemistry C</i> , <b>2020</b> , 8, 13557-13562	7.1	13

214	Metal-Semiconductor-Metal GeSn Photodetectors on Silicon for Short-Wave Infrared Applications. <i>Micromachines</i> , <b>2020</b> , 11,	3.3	14
213	Three-Dimensional Capacitor Embedded in Fully Cu-Filled Through-Silicon Via and Its Thermo-Mechanical Reliability for Power Delivery Applications <b>2020</b> ,		2
212	Insights into the Origins of Guided Microtrenches and Microholes/rings from Sn Segregation in Germanium Tin Epilayers. <i>Journal of Physical Chemistry C</i> , <b>2020</b> , 124, 20035-20045	3.8	4
211	Assembly Process and Electrical Properties of Top-Transferred Graphene on Carbon Nanotubes for Carbon-Based 3-D Interconnects. <i>IEEE Transactions on Components, Packaging and Manufacturing Technology</i> , <b>2020</b> , 10, 516-524	1.7	4
210	Band structure of Ge1⊠ Sn x alloy: a full-zone 30-band k ⊡p model. <i>New Journal of Physics</i> , <b>2019</b> , 21, 073037	2.9	13
209	Thermally Reflowed Die-Attached Linear Variable Optical Filter for Mid-Infrared Volatile Organic Compounds Detection. <i>Journal of Microelectromechanical Systems</i> , <b>2019</b> , 28, 824-832	2.5	O
208	3D Integration of CMOS-Compatible Surface Electrode Ion Trap and Silicon Photonics for Scalable Quantum Computing <b>2019</b> ,		2
207	Electrical properties of FCVA deposited nano-crystalline graphitic carbon thin films with in situ treatment techniques. <i>EPJ Applied Physics</i> , <b>2019</b> , 85, 20301	1.1	
206	Deposited poly-Si as on-demand linewidth compensator for on-chip Fabry Perot interferometer and vertical linear variable optical filter bandpass and passband manipulation. <i>Journal of Micromechanics and Microengineering</i> , <b>2019</b> , 29, 047001	2	3
205	GaN HEMTs with Breakdown Voltage of 2200 V Realized on a 200 mm GaN-on-Insulator(GNOI)-on-Si Wafer <b>2019</b> ,		2
204	GrapheneMetal Nanoparticles for Enhancing Thermoelectric Power Factor. <i>IEEE Nanotechnology Magazine</i> , <b>2019</b> , 18, 1114-1118	2.6	3
203	Metal-semiconductor-metal photodetectors on a GeSn-on-insulator platform <b>2019</b> ,		3
202	Optical design considerations of rear-side dielectric for higher efficiency of PERC solar cells. <i>Optics Express</i> , <b>2019</b> , 27, A758-A765	3.3	6
201	Integrating GeSn photodiode on a 200 mm Ge-on-insulator photonics platform with Ge CMOS devices for advanced OEIC operating at 2 fb band. <i>Optics Express</i> , <b>2019</b> , 27, 26924-26939	3.3	18
200	Design Considerations and Fabrication Challenges of Surface Electrode Ion Trap with TSV Integration <b>2019</b> ,		1
199	TiN Guard Ring Around TSV for Cross-Talk Suppression of Parallel Networking of Data Center 2019,		2
198	Guest Editorial Special Section on the Second Electron Devices Technology and Manufacturing (EDTM) Conference 2019. <i>IEEE Journal of the Electron Devices Society</i> , <b>2019</b> , 7, 1200-1200	2.3	
197	Dark Current Analysis of Vertical p-i-n Photodetectors on a Germanium-on-Insulator Platform <b>2019</b> ,		1

196	Germanium Photodetectors with 60-nm Absorption Coverage Extension and ~2 Quantum Efficiency Enhancement across L-Band <b>2019</b> ,		1
195	Development and Integration of Silicon Photonics Interposer for Quantum Computing System <b>2019</b> ,		1
194	Cullu Bonding in Ambient Environment by Ar/N2 Plasma Surface Activation and Its Characterization. <i>IEEE Transactions on Components, Packaging and Manufacturing Technology</i> , <b>2019</b> , 9, 596-605	1.7	6
193	Strain relaxation of germanium-tin (GeSn) fins. AIP Advances, 2018, 8, 025111	1.5	5
192	Curvature evolution of 200 mm diameter GaN-on-insulator wafer fabricated through metalorganic chemical vapor deposition and bonding. <i>Japanese Journal of Applied Physics</i> , <b>2018</b> , 57, 051002	1.4	1
191	Novel three-dimensional carbon nanotube networks as high performance thermal interface materials. <i>Carbon</i> , <b>2018</b> , 132, 359-369	10.4	23
190	Suppression of interfacial voids formation during silane (SiH4)-based silicon oxide bonding with a thin silicon nitride capping layer. <i>Journal of Applied Physics</i> , <b>2018</b> , 123, 015302	2.5	10
189	Monolithic Integration of Si-CMOS and III-V-on-Si Through Direct Wafer Bonding Process. <i>IEEE Journal of the Electron Devices Society</i> , <b>2018</b> , 6, 571-578	2.3	16
188	Charging of miniature flat heat pipes. Heat and Mass Transfer, 2018, 54, 3131-3136	2.2	
187	High-performance GeSn photodetector and fin field-effect transistor (FinFET) on an advanced GeSn-on-insulator platform. <i>Optics Express</i> , <b>2018</b> , 26, 10305-10314	3.3	16
186	GeSn lateral p-i-n photodetector on insulating substrate. <i>Optics Express</i> , <b>2018</b> , 26, 17312-17321	3.3	25
185	Impacts of doping on epitaxial germanium thin film quality and Si-Ge interdiffusion. <i>Optical Materials Express</i> , <b>2018</b> , 8, 1117	2.6	9
184	High-efficiency normal-incidence vertical p-i-n photodetectors on a germanium-on-insulator platform: publisher note. <i>Photonics Research</i> , <b>2018</b> , 6, 46	6	3
183	Germanium-Tin (GeSn) P-Channel Fin Field-Effect Transistor Fabricated on a Novel GeSn-on-Insulator Substrate. <i>IEEE Transactions on Electron Devices</i> , <b>2018</b> , 65, 3754-3761	2.9	19
182	High-performance AlGaInP light-emitting diodes integrated on silicon through a superior quality germanium-on-insulator. <i>Photonics Research</i> , <b>2018</b> , 6, 290	6	6
181	Optimization and thermal characterization of uniform silicon micropillar based evaporators. <i>International Journal of Heat and Mass Transfer</i> , <b>2018</b> , 127, 51-60	4.9	19
180	Dielectric Quality of 3D Capacitor Embedded in Through-Silicon Via (TSV) 2018,		1
179	Modeling, Fabrication, and Characterization of 3-D Capacitor Embedded in Through-Silicon Via. <i>IEEE Transactions on Components, Packaging and Manufacturing Technology</i> , <b>2018</b> , 8, 1524-1532	1.7	4

178	Thermal design optimization of evaporator micropillar wicks. <i>International Journal of Thermal Sciences</i> , <b>2018</b> , 134, 179-187	4.1	9	
177	Leakage current conduction mechanism of three-dimensional capacitors embedded in through-silicon vias. <i>Japanese Journal of Applied Physics</i> , <b>2018</b> , 57, 07MF01	1.4	1	
176	Germanium-on-insulator Pedestal Waveguide for Midinfrared Sensing Applications 2018,		1	
175	A self-aligned dry etching method for mechanical strain enhancement of germanium and its uniformity improvement for photonic applications <b>2018</b> ,		2	
174	GeSn p-FinFETs with Sub-10 nm Fin Width Realized on a 200 mm GeSnOI Substrate: Lowest SS of 63 mV/decade, Highest Gm,int of 900 μS/μm, and High-Field μeff of 275 cm2/V <b>8 2018</b> ,		1	
173	Fabrication and Characterization of Surface Electrode Ion Trap for Quantum Computing 2018,		3	
172	. IEEE Journal of Photovoltaics, <b>2018</b> , 8, 1627-1634	3.7	2	
171	Effects of Copper Migration on the Reliability of Through-Silicon Via (TSV). <i>IEEE Transactions on Device and Materials Reliability</i> , <b>2018</b> , 18, 520-528	1.6	4	
170	Formation of 45 <sup>a</sup> Silicon (110) Surface Using Triton X-nSurfactants in Potassium Hydroxide for Infrared Applications. <i>ECS Journal of Solid State Science and Technology</i> , <b>2018</b> , 7, Q259-Q266	2		
169	In0.49Ga0.51P/GaAs heterojunction bipolar transistors (HBTs) on 200 mm Si substrates: Effects of base thickness, base and sub-collector doping concentrations. <i>AIP Advances</i> , <b>2018</b> , 8, 115132	1.5	4	
168	MOCVD growth of InGaP/GaAs heterojunction bipolar transistors on 200 mm Si wafers for heterogeneous integration with Si CMOS. <i>Semiconductor Science and Technology</i> , <b>2018</b> , 33, 115011	1.8	3	
167	Performance of AlGainP LEDs on silicon substrates through low threading dislocation density (TDD) germanium buffer layer. <i>Semiconductor Science and Technology</i> , <b>2018</b> , 33, 104004	1.8	5	
166	Spiral Waveguides on Germanium-on-Silicon Nitride Platform for Mid-IR Sensing Applications. <i>IEEE Photonics Journal</i> , <b>2018</b> , 10, 1-7	1.8	17	
165	Online Condition Monitoring System for DC-Link Capacitor in Industrial Power Converters. <i>IEEE Transactions on Industry Applications</i> , <b>2018</b> , 54, 4775-4785	4.3	23	
164	Hetero-epitaxy of high quality germanium film on silicon substrate for optoelectronic integrated circuit applications. <i>Journal of Materials Research</i> , <b>2017</b> , 32, 4025-4040	2.5	10	
163	Germanium-on-insulator virtual substrate for InGaP epitaxy. <i>Materials Science in Semiconductor Processing</i> , <b>2017</b> , 70, 17-23	4.3		
162	Fabrication and characterization of single junction GaAs solar cells on Si with As-doped Ge buffer. <i>Solar Energy Materials and Solar Cells</i> , <b>2017</b> , 172, 140-144	6.4	21	
161	The first GeSn FinFET on a novel GeSnOI substrate achieving lowest S of 79 mV/decade and record high Gm, int of 807 B/fh for GeSn P-FETs <b>2017</b> ,		15	

160	Physical and Electrical Characterization of 3D Embedded Capacitor: A High-Density MIM Capacitor Embedded in TSV <b>2017</b> ,		5
159	Observations of copper (Cu) transport in through-silicon vias (TSV) structure by electrical characterization for its reliability evaluation <b>2017</b> ,		3
158	The GaAs/GaAs/Si solar cell ©rowards current matching in an integrated two terminal tandem. <i>Solar Energy Materials and Solar Cells</i> , <b>2017</b> , 160, 94-100	6.4	15
157	Germanium-on-insulator virtual substrate for InGaP epitaxy. <i>Materials Science in Semiconductor Processing</i> , <b>2017</b> , 58, 15-21	4.3	4
156	Dielectric relaxation in AC powder electroluminescent devices. <i>Solid State Communications</i> , <b>2017</b> , 250, 53-56	1.6	6
155	Low-threshold optically pumped lasing in highly strained germanium nanowires. <i>Nature Communications</i> , <b>2017</b> , 8, 1845	17.4	80
154	Thermal stability of germanium-tin (GeSn) fins. Applied Physics Letters, 2017, 111, 252103	3.4	6
153	Online equivalent series resistance estimation method for condition monitoring of DC-link capacitors <b>2017</b> ,		7
152	Extension of Germanium-on-insulator optical absorption edge using CMOS-compatible silicon nitride stressor <b>2017</b> ,		2
151	Growth and fabrication of carbon-based three-dimensional heterostructure in through-silicon vias (TSVs) for 3D interconnects <b>2017</b> ,		2
150	2017,		2
149	Reliability Evaluation of Copper (Cu) Through-Silicon Vias (TSV) Barrier and Dielectric Liner by Electrical Characterization and Physical Failure Analysis (PFA) <b>2017</b> ,		4
148	Temperature enhanced spontaneous emission rate spectra in GeSn/Ge quantum wells. <i>Optical Materials Express</i> , <b>2017</b> , 7, 800	2.6	7
147	High-efficiency normal-incidence vertical p-i-n photodetectors on a germanium-on-insulator platform. <i>Photonics Research</i> , <b>2017</b> , 5, 702	6	36
146	Opto-impedance spectroscopy and equivalent circuit analyses of AC powder electroluminescent devices. <i>Optics Express</i> , <b>2017</b> , 25, A454-A466	3.3	10
145	Optimization and thermal characterization of uniform micropillar based silicon evaporator in advanced vapor chambers <b>2016</b> ,		1
144	Detailed thermal resistance model for characterization of the overall effective thermal conductivity of a flat heat pipe <b>2016</b> ,		0
143	Thin Film Silicon Nanowire/PEDOT:PSS Hybrid Solar Cells with Surface Treatment. <i>Nanoscale Research Letters</i> , <b>2016</b> , 11, 311	5	18

#### (2016-2016)

142	Novel integration of ultrathin Al2O3with low-kdielectric as bilayer liner for capacitance optimization and stress mitigation in Cu through-silicon-via. <i>Japanese Journal of Applied Physics</i> , <b>2016</b> , 55, 04EC08	1.4	
141	(Invited) The Effect of Germanium/Silicon Interface on Germanium Photonics. <i>ECS Transactions</i> , <b>2016</b> , 75, 683-688	1	1
140	Through-substrate via (TSV) with embedded capacitor as an on-chip energy storage element <b>2016</b> ,		5
139	Experiments on the Biporous Micropillar Array for Enhanced Heat Transfer Performance <b>2016</b> ,		1
138	Graphene INT hetero-structure for next generation interconnects. RSC Advances, 2016, 6, 53054-53061	3.7	15
137	Red InGaP light-emitting diodes epitaxially grown on engineered Ge-on-Si substrates <b>2016</b> ,		2
136	High-Efficiency Planar Thin-Film Si/PEDOT:PSS Hybrid Solar Cell. <i>IEEE Journal of Photovoltaics</i> , <b>2016</b> , 6, 217-222	3.7	2
135	Geometry and Thermal Stress Analysis of In-plane Outgassing Channels in Al2O3-Intermediated InP (Die)-to-Si (Wafer) Bonding. <i>ECS Journal of Solid State Science and Technology</i> , <b>2016</b> , 5, P117-P123	2	O
134	Epitaxy and characterization of GaInP/AlInP light-emitting diodes on As-doped Ge/Si substrates. <i>Optics Express</i> , <b>2016</b> , 24, 23129-23135	3.3	3
133	On the origins of near-surface stresses in silicon around Cu-filled and CNT-filled through silicon vias. <i>Semiconductor Science and Technology</i> , <b>2016</b> , 31, 055008	1.8	2
132	Experiments on the ultrathin silicon vapor chamber for enhanced heat transfer performance 2016,		3
131	Reduction of threading dislocation density in Ge/Si using a heavily As-doped Ge seed layer. <i>AIP Advances</i> , <b>2016</b> , 6, 025028	1.5	41
130	Maximum boost space vector modulated three-phase three-level neutral-point-clamped quasi-Z-source inverter <b>2016</b> ,		2
129	GeSn-on-insulator substrate formed by direct wafer bonding. <i>Applied Physics Letters</i> , <b>2016</b> , 109, 022106	3.4	25
128	Cu-Cu Die to Die Surface Activated Bonding in Atmospheric Environment Using Ar and Ar/N2 Plasma. <i>ECS Transactions</i> , <b>2016</b> , 75, 109-116	1	4
127	(Invited) Novel Integrated Circuit Platforms Employing Monolithic Silicon CMOS + GaN Devices. <i>ECS Transactions</i> , <b>2016</b> , 75, 31-37	1	5
126	Enhanced copper micro/nano-particle mixed paste sintered at low temperature for 3D interconnects. <i>Applied Physics Letters</i> , <b>2016</b> , 108, 263103	3.4	22
125	Germanium-on-silicon nitride waveguides for mid-infrared integrated photonics. <i>Applied Physics Letters</i> , <b>2016</b> , 109, 241101	3.4	47

124	Non-destructive degradation study of copper wire bond for its temperature cycling reliability evaluation. <i>Microelectronics Reliability</i> , <b>2016</b> , 61, 56-63	1.2	3
123	Color tunable hybrid AC powder electroluminescent devices with organic fluorescent materials. <i>Optical Materials Express</i> , <b>2016</b> , 6, 2879	2.6	15
122	(Invited) SiGe and III-V Materials and Devices: New HEMT and LED Elements in 0.18-Micron CMOS Process and Design. <i>ECS Transactions</i> , <b>2016</b> , 75, 439-446	1	12
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